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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
09/925,579	08/09/2001	Akira Nakano	9281-4140	2869
7590 07/22/2004			EXAMINER	
Brinks Hofer Gilson & Lione P.O. Box 10395			ZERVIGON, RUDY	
Chicago, IL 60610			ART UNIT	PAPER NUMBER
			1763	
			DATE MAILED: 07/22/2004	

Please find below and/or attached an Office communication concerning this application or proceeding.

	Application No.	Applicant(s)
Office Action Summary	09/925,579	NAKANO ET AL.
Onice Action Summary	Examiner	Art Unit
The MAII INC DATE of this communication and	Rudy Zervigon	1763
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the	correspondence address
A SHORTENED STATUTORY PERIOD FOR REPL' THE MAILING DATE OF THIS COMMUNICATION.  - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a repl If NO period for reply is specified above, the maximum statutory period  - Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be y within the statutory minimum of thirty (30) d will apply and will expire SIX (6) MONTHS froe, cause the application to become ABANDON	timely filed  ays will be considered timely.  m the mailing date of this communication.  IED (35 U.S.C. § 133).
Status		
Responsive to communication(s) filed on <u>09 A</u> This action is <b>FINAL</b> . 2b) ☑ This      Since this application is in condition for alloware closed in accordance with the practice under B	s action is non-final. nce except for formal matters, p	
Disposition of Claims		
<ul> <li>4)  Claim(s) 1-62 is/are pending in the application 4a) Of the above claim(s) is/are withdray</li> <li>5)  Claim(s) is/are allowed.</li> <li>6)  Claim(s) is/are rejected.</li> <li>7)  Claim(s) is/are objected to.</li> <li>8)  Claim(s) 1-62 are subject to restriction and/or</li> </ul>	wn from consideration.	
Application Papers		
9) The specification is objected to by the Examine 10) The drawing(s) filed on is/are: a) acc Applicant may not request that any objection to the Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Example 11.	epted or b) objected to by the drawing(s) be held in abeyance. Stion is required if the drawing(s) is constant.	ee 37 CFR 1.85(a). bjected to. See 37 CFR 1.121(d).
Priority under 35 U.S.C. § 119		
12) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of:  1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the prio application from the International Burear * See the attached detailed Office action for a list	es have been received. es have been received in Applica rity documents have been recei u (PCT Rule 17.2(a)).	ution No ved in this National Stage
Attachment(s)	A	n: (DTO 442)
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date</li> </ol>	4) Interview Summa Paper No(s)/Mail 5) Notice of Informal 6) Other:	

## **DETAILED ACTION**

#### Election/Restrictions

- 1. Restriction to one of the following inventions is required under 35 U.S.C. 121:
  - Claims 1-9, drawn to a plasma processing apparatus, classified in class 118, subclass 723E.
  - II. Claims 10-12, and 51-62, drawn to a performance validation system, classified in class 118, subclass 698.
  - III. Claims 13-50, drawn to plasma processing chamber units, classified in class 118, subclass 719.

The inventions are distinct, each from the other because of the following reasons:

- 2. Inventions I and II are unrelated. Inventions are unrelated if it can be shown that they are not disclosed as capable of use together and they have different modes of operation, different functions, or different effects (MPEP § 806.04, MPEP § 808.01). In the instant case the different inventions have different modes of operation (plasma containment and processing vs. plasma processing control), different functions (wafer processing vs. wafer processing control), and different effects (wafer film generation vs. process optimization).
- 3. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.
- 4. Inventions II and III are unrelated. Inventions are unrelated if it can be shown that they are not disclosed as capable of use together and they have different modes of operation, different functions, or different effects (MPEP § 806.04, MPEP § 808.01). In the instant case the different

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inventions have different modes of operation (plasma containment and processing vs. plasma processing control), different functions (wafer processing vs. wafer processing control), and different effects (wafer film generation vs. process optimization).

- 5. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.
- 6. Inventions I and III are unrelated. Inventions are unrelated if it can be shown that they are not disclosed as capable of use together and they have different modes of operation, different functions, or different effects (MPEP § 806.04, MPEP § 808.01). In the instant case the different inventions have different modes of operation (plasma containment and wafer processing vs. wafer transport and processing), different functions (plasma wafer processing vs. wafer transport and plasma processing), and different effects (wafer plasma processing vs. wafer transport and processing).
- 7. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.
- 8. Applicant is reminded that upon the cancellation of claims to a non-elected invention, the inventorship must be amended in compliance with 37 CFR 1.48(b) if one or more of the currently named inventors is no longer an inventor of at least one claim remaining in the application. Any amendment of inventorship must be accompanied by a request under 37 CFR 1.48(b) and by the fee required under 37 CFR 1.17(i).

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### Conclusion

9. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Rudy Zervigon whose telephone number is (571) 272.1442. The examiner can normally be reached on a Monday through Thursday schedule from 8am through 7pm. The official fax phone number for the 1763 art unit is (703) 872-9306. Any Inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Chemical and Materials Engineering art unit receptionist at (571) 272-1700. If the examiner can not be reached please contact the examiner's supervisor, Gregory L. Mills, at (571) 272-1439.